

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/664,739
Filing Date September 18, 2003
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 2818
Examiner Dung Le
Attorney's Docket No. MI22-2340
Title: Methods for Conditioning Surfaces of Polishing Pads After
Chemical-Mechanical Polishing



SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

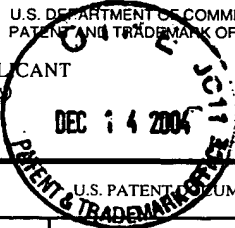
Respectfully submitted,

Dated: December 14, 2004

By: Jennifer J. Taylor
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Reg. No. 48,711

EV372470568

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2340	SERIAL NO. 10/664,739
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Sujit Sharan et al.	
				FILING DATE September 18, 2003	GROUP 2818



U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,970,373	10-1999	Allen			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AM							
AN							
AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
AR			
AS			
AT			

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.